

Special Issue

Amorphous Oxide Semiconductor-Based Memristive Devices and Thin-Film Transistors

Message from the Guest Editors

We invite researchers and scientists to showcase their work in this Special Issue with research papers and review articles that focus on trends in AOS-based memristors, thin-film transistors, diodes and integration strategies, modelling, and simulation, from fundamental research to applications.

- Solution-based technology (coating and printing techniques)
- AOS memristive devices and systems
- neuromorphic computing with AOS-based memristors
- pattern recognition based on AOS memristors
- integration of AOS memristors with TFTs
- system-on-panel applications
- novel circuits on AOS-based memristors
- modeling and simulation of AOS processes for memristive devices
- circuit models and simulation of AOS memristors and TFTs
- resistive RAM based on AOS materials

Guest Editors

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